Referenčna oznaka	Naslov
101/646/NP	PNW TS 101-646 ED1: Electrostatics ? Part 6-2: Electrostatic control in healthcare, commercial and public facilities ? Public spaces and office areasElectrostatics ? Part 6-2: Electrostatic control in healthcare, commercial and public facilities ? Public spaces and office areas
110/1383/NP	PNW 110-1383 ED1: Durability test methods for electronic displays ? Part 3-2: Mechanical tests ? Static stress
110/1384/NP	PNW 110-1384 ED1: Durability test methods for electronic displays ? Part 2-21: Environmental tests - Test methods for heat and humidity
110/1387/NP	PNW 110-1387 ED1: Future IEC 62977-2-8: Electronic Displays ? Part 2-8: Measurements of optical characteristics ? Reflective displays
110/1393/NP	PNW 110-1393 ED1: Flexible display devices - Part 6-42: Flattening force measurement methods
110/1394/NP	PNW 110-1394 ED1: Eyewear display - Part 202: Specific measurement methods for emissive micro-display devices
110/1395/NP	PNW 110-1395 ED1: Organic light emitting diode (OLED) displays - Part 6-6: Image retention measurement method
110/1396/NP	PNW 110-1396 ED1: Organic light emitting diode (OLED) displays - Part 6-7: Measuring methods of optical characteristics for under screen feature
101/646/NP	PNW TS 101-646 ED1: Electrostatics ? Part 6-2: Electrostatic control in healthcare, commercial and public facilities ? Public spaces and office areasElectrostatics ? Part 6-2: Electrostatic control in healthcare, commercial and public facilities ? Public spaces and office areas
129/10/NP	PNW 129-10 ED1: Terminology for Electric Power Robots
34/895/NP	PNW 34-895 ED1: Digital addressable lighting interface ? Part 306: Particular requirements ? Input devices ? General purpose sensor
47F/396/NP	PNW 47F-396 ED1: Semiconductor devices - Micro-electromechanical devices - Part 44: Test methods for dynamic performances of MEMS resonant electric-field-sensitive devices
47F/397/NP	PNW 47F-397 ED1: Semiconductor devices - Micro-electromechanical devices - Part 45: Silicon based MEMS fabrication technology-Measurement method of impact resistance of nanostructures
47F/398/NP	PNW 47F-398 ED1: Semiconductor devices - Micro-electromechanical devices - Part 46: Silicon based MEMS fabrication technology ? Measurement method of tensile strength of nano-scale membrane

47F/399/NP	PNW 47F-399 ED1: Semiconductor devices - Micro-electromechanical devices - Part 47: Silicon based MEMS fabrication technology - Measurement method of bending strength of microstructures
48B/2936/NP	PNW 48B-2936 ED1: Connectors for electrical and electronic equipment ? Tests and measurements ? Part 99-003: Endurance test schedules ? Test 99c: Test schedule for balanced single pair connectors unmating under electrical load
59M/145/NP	PNW 59M-145 ED1: Test standard for refrigerated appliances for use with distributed renewable energy sources (off grid) or weak grid
69/813/NP	PNW 69-813 ED1: ISO 15118-21: Road vehicles ? Vehicle to grid communication interface ? Part 21: Common 2nd generation network layer and application layer requirements conformance test plan
87/785/NP	PNW 87-785 ED1: Ultrasonics - Measurement of biologically relevant temperature rise produced by medical ultrasonic equipment
129/10/NP	PNW 129-10 ED1: Terminology for Electric Power Robots
JTC1-SC41/257/NP	PNW JTC1-SC41-257 ED1: Internet of Things (IoT) ? Device model for IoT device interoperability
SyCSmartEnergy/197/NP	PNW TS SYCSMARTENERGY-197 ED1: Distributed Energy Resource Aggregation Business System: Architecture and Service scenario